

ITW
Docket No.: ISH-0227
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Toshihiro TSUCHIYA

Application No.: 10/523,976

Confirmation No.: 1124

Filed: February 8, 2005

Art Unit: 3723

For: WAFER POLISHING METHOD AND
APPARATUS

Examiner: Not Assigned Yet

REQUEST FOR CORRECTED FILING RECEIPT

VIA FACSIMILE: 703-746-9195

Attention: Office of Initial Patent Examination's
Customer Service Center

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Sir or Madam:

1. Attached is a copy of the official filing receipt received from the PTO in the above application for which issuance of a corrected filing receipt is respectfully requested. Also enclosed is the first page of the executed declaration showing the correct data.
2. There is an error with respect to the following, which is incorrectly entered.

Error:

1. Title

Correct data:

1. WAFER POLISHING METHOD AND
APPARATUS

The correction is due to an error by the USPTO. If any fee is due, please charge Deposit Account No. 18-0013.

Dated: 09-23-2005

Tel. No.: (202) 955-3750

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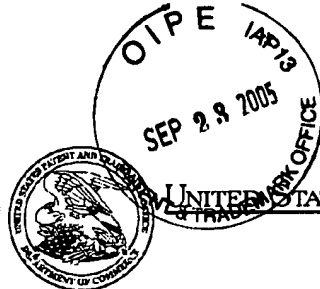
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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/523,976	02/08/2005	3723	900	ISH-0227	8	8	1

CONFIRMATION NO. 1124

FILING RECEIPT

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23353
 RADER FISHMAN & GRAUER PLLC
 LION BUILDING
 1233 20TH STREET N.W., SUITE 501
 WASHINGTON, DC 20036

Date Mailed: 08/30/2005

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. **If an error is noted on this Filing Receipt, please mail to the Commissioner for Patents P.O. Box 1450 Alexandria Va 22313-1450. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).**

Applicant(s)

Toshihiro Tsuchiya, Fukushima, JAPAN;

Power of Attorney: The patent practitioners associated with Customer Number 23353.

Domestic Priority data as claimed by applicant

This application is a 371 of PCT/JP03/09658 07/30/2003

Foreign Applications

JAPAN 2002-232693 08/09/2002

Projected Publication Date: 12/01/2005

Non-Publication Request: No

Early Publication Request: No

Title

Method and apparatus for polishing wafer

Preliminary Class

451

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